

labFlex® 200

Lab sputter roll coater

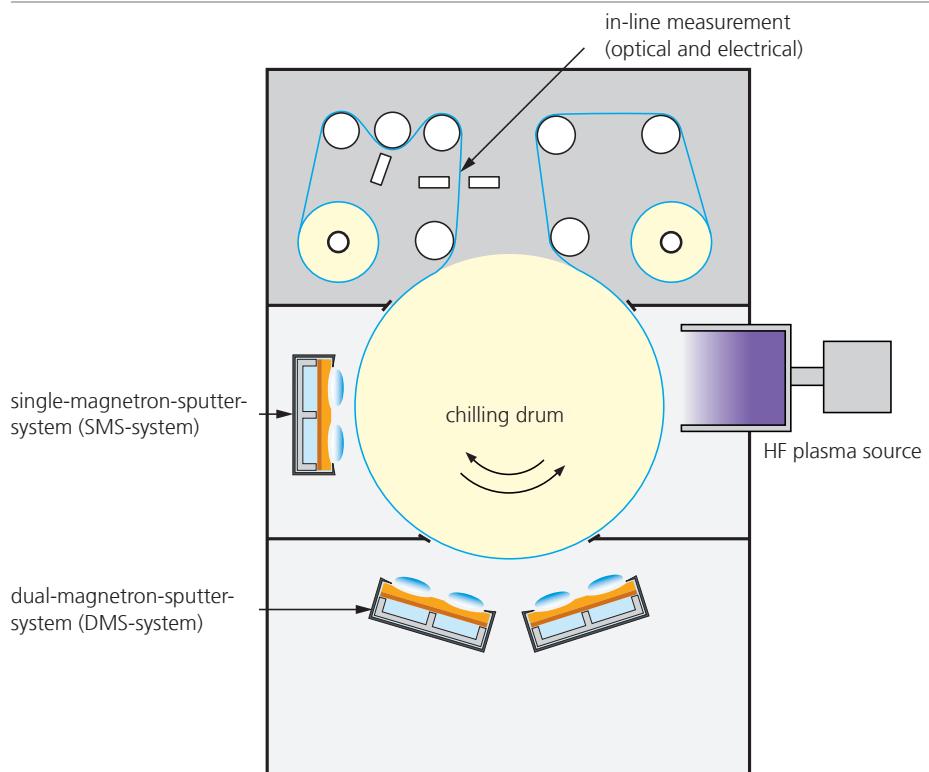


Fraunhofer
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Technical specifications

deposition width	200 mm
web thickness	12 ... 200 µm
web speed	0.1 ... 6 m/min
sputter equipment	<ul style="list-style-type: none"> • dual-magnetron-sputter-system (DMS-system) • single-magnetron-sputter-system (SMS-system) • ion source • HF plasma source
separately pumped zones	3
layer material	metals, TiO ₂ , SiO ₂ , Nb ₂ O ₅ , ITO, ZAO, SnO ₂ , HfO ₂ , WO ₃ , TiN, Si ₃ N ₄ , ZrO ₂
In-situ monitoring	<ul style="list-style-type: none"> • optical transmission + reflection • sheet resistance

Scheme



Technology

Pulse magnetron sputtering

- dual-magnetron-sputtering
- magnetron-PECVD
- in-line pretreatment
- comprehensive and overall process development for deposition of layer stacks under production-like conditions
- plasma polymerization
- DC-sputtering

Business unit

Coating of flexible products

The refinement of surfaces of plastic films and other flexible materials with thin layers enables the usage of these materials for a wide range of innovative products.

In the Fraunhofer FEP, vacuum roll-to-roll and batch-type coating systems are used for the development of cost efficient production processes. This includes the layer stack design as well as the development of the coating technologies.

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